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			Hagemeyer et al.		70	820 1
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		US PA	ATENT DOCUMENTS			
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	DATE
EQ	4,705,669	11/10/87	Tsuji et al.	422	93	8/27/86
150	4,869,282	9/26/89	Sittler et al.	137	15	12/09/88
W	5,776,359	7/07/98	Schultz et al	252	62.51	5/08/95
190	5,780,748	7/14/98	Barth	73	861.47	1/29/97
W	5,842,787	12/1/98	Kopf-Sill et al.	366	340	10/9/97
EV	5,865,417	2/2/99	Harris et al.	251	11	9/27/96
60	5,922,591	7/13/99	Anderson et al.	435	287.2	6/27/96
<i>EQ</i>	5,927,325	7/27/99	Bensaoula et al.	137	599	10/25/96
V Q	5,959,297	9/28/99	Weinberg et al	250	288	10/8/97
FQ	5,985,356	11/16/99	Schultz et al	427	8	10/18/94
W	6,004,617	12/21/99	Schultz et al	427	8	6/07/95
1/4	6,030,917	2/29/00	Weinberg et al	502	104	7/22/97
10	6,063,633	5/16/00	Willson	436	37	6/17/96
(1)Q-	6,087,181	7/11/00	Cong	436	37	3/16/98
W	6,149,882	11/21/00	Guan et al	422	211	6/09/98
102	6,175,409	1/16/01	Nielsen et al	356	337	4/02/99
100	US-20020014106	2/07/02	Srinivasan et al.	1		3/07/01
10	US-20020042140	4/11/02	Hagemeyer et al.			7/09/01
W.T.	US-20020045265	4/18/02	Bergh et al.			3/08/01
100	US-20020048536	4/25/02	Bergh et al.	+	1	3/07/01

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		r On	EIGH DOCOMENTS				
EXAMINER'S INITIALS	PATENT NO. DATE		COUNTRY	CLASS	SUB CLASS	TRANSLATION YES NO	
11	DE 27 14 939 B2	11/29/79	Germany	G01N	31/10		X
60	DE 196 32 779 A1	2/19/98	Germany	G01N	35/00	х	
EQ	DE 198 05 719 A1	8/19/99	Germany	B01J	35/04	х	
W	DE 198 06 848 A1	8/19/99	Germany	B01J	35/02	х	
EQ.	DE 198 09 477 A1	9/16/99	Germany	G01N	31/10	х	
KIG	EP 0 796 654 A2	9/24/97	EPO	B01J	19/00		х
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AUG 1 9 200Z ATTORNEY'S DOCKET NO .: APPLICATION NO.: HEORNA TION DISCLOSURE TC 1700 99-34R1 09/901,858 **CITATION** PTO-1449 APPLICANT: Hagemeyer et al. FILING DATE: GROUP: 7/9/2001 1764 **FOREIGN DOCUMENTS EXAMINER'S** PATENT NO. DATE COUNTRY **CLASS** SUB TRANSLATION INITIALS CLASS YES NO WO 97/32208 9/04/97 PCT **G01N** 31/10 WO 98/03521 1/29/98 PCT C07F 19/00 WO 98/07026 2/19/98 PCT **G01N** 31/10 X WO 98/13137 4/02/98 PCT **B01J** 19/00 X WO 98/13605 4/02/98 PCT F15C 5/00 х WO 98/53236 11/26/98 PCT F16K 31/126 х WO 99/41005 8/19/99 PCT B01J 19/00 X WO 00/09255 EUR 2/24/00 PCT B01J 19/00 WO 00/14529 3/16/00 PCT G01N 31/02 KIQ WO 00/17413 3/30/00 PCT C23C 14/04 PU WO 00/51720 9/08/00 PCT B01J 19/00 X WO 01/00315 1/0 1/04/01 PCT **B01J** 19/00 х WO 01/66245 9/13/01 PCT **B01J** 19/00 OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages etc.) Berenschot, J.W., et al., "Micromachining of {111} Plates in <001> Oriented Silicon", J. Micromech. Microeng. 8 (1998) 104-107 Bruns, Mark W., "The Application of Silicon Micromachining Technology and High Speed Gas Chromatography to On-Line Process Control", MTI Analytical Instruments Bruns, Mark W., "Silicon Micromachining and High Speed Gas Chromatography", IEEE, 1992, pp. W 1640-1644 w Grosjean et al., "A Practical Thermopneumatic Valve", IEEE, 1999, pp. 147-152 Haswell, Stephen J. et al., "The Application of Micro Reactors to Synthetic Chemistry", Chem. ED Commun., 2001, 391-398 Hendrix, Charles D., "What Every Technologist Should Know About Experimental Design", Chemtech, W 1979, pp. 167-174 Henning, Albert K. et al., "Microfluidic MEMS for Semiconductor Processing", IEEE, 1998, Vol. 21, TI pp. 329-337

Hinderling, Christian et al., "Rapid Screening of Olefin Polymerization Catalyst Libraries by Electrospray Ionization Tandem Mass Spectrometry", Angew. Chem. Int. Ed., 1999, 38, No. 15,

Technology, 1997, 1(6): 367-374

Control Applications"

Lambert, Richard H. et al., "Utilization of a Portable Microchip Gas Chromatograph to Identify and Reduce Fugitive Emissions at a Pharmaceutical Manufacturing Plant", Field Analytical Chemistry and

Oosterbroek, R.E. et al., "Utilizing the {111} Plane Switch-Over Etching Process for Micro Fluid

Ali6 1 9 2002		Sheet 3 of 3					
12 &	ATTORNEY'S DOCKET NO.:	APPLICATION NO.:					
PADE CITATION	99-34R1	09/901,858					
PTO-1449	APPLICANT:						
	Hagemeyer et al.	GROUP:					
	FILING DATE: 7/9/2001	GROUP: 1764					
OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages etc.)							
Pérez-Ramírez, J. et al., "The Six-F Kinetic Studies", Catalysis Today, 2	Pérez-Ramírez, J. et al., "The Six-Flow Reactor Technology-A Review on Fast Catalyst Screening and Kinetic Studies", Catalysis Today, 2000, 60, 93-109						
	Rich et al., "An 8-Bit Microflow Controller Using Pneumatically-Actuated Valves", IEEE, 1999.						
Sadler, Daniel J. et al., "A New Mag Applications", Center for Microelect	Sadler, Daniel J. et al., "A New Magnetically Actuated Microvalve For Liquid and Gas Control Applications", Center for Microelectronic Sensors and MEMS, University of Cincinnati						
€ Wang et al., "A Parylene Micro Che	Wang et al., "A Parylene Micro Check Valve", IEEE, 1999, pp. 177-182						
Wijngaarden et al., "Industrial Catal	Wijngaarden et al., "Industrial Catalysts - Optimizing Catalysts and Processes", Wiley-VCH, Germany						
(1998).							
TRF, Solid State Sensor and Actual pp 251-255	Zdeblick et al., "Thermopneumatically Actuated Microvalves and Integrated Electro-Fluidic Circuits", TRF, Solid State Sensor and Actuator Workshop, Hilton Head, South Carolina, June 13-16, 1994, pp 251-255						
EXAMINER: Glewboth hum DATE CONSIDERED: 2/18/2009							

Examiner: Initial if feference considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.